In the Abstract:

On page 31, replace the Abstract paragraph starting at line 2 as follows:

A system is provided for the collection of measurements for use by a surface profiling processing scheme. A movable platform has means mounted thereon for is equipped to: (i) generating generate a measurement of inclination of a surface where the movable when the platform is positioned and stationary thereon, (ii) generating generate measurements of surface curvature of the surface as the movable platform traverses the surface, (iii) monitoring monitor distance that the movable platform traverses during a measurement run on the surface where a measurement run is defined by starting and stopping positions on the surface that are spaced apart from one another, (iv) generating generate a signal each time the movable platform traverses a predetermined amount of distance during a measurement run where the signal sogenerated serves as an indication is such that the user is alerted to stop the movable platform during the measurement run, (v) collecting collect measurements of curvature while the movable platform traverses the surface during the measurement run, and (vi) collecting measurement collect measurements of inclination at the starting position, stopping position, and each time the movable platform is stopped during the measurement run.